

Title (en)

Apparatus for the thermal treatment of harmful substances in process offgases

Title (de)

Vorrichtung zur thermischen Behandlung von Schadstoffe enthaltenden Prozessabgasen

Title (fr)

Appareil pour le traitement thermique de substances nocives dans des gases de procédés

Publication

EP 1517083 B1 20080123 (DE)

Application

EP 04021022 A 20040903

Priority

DE 10342692 A 20030909

Abstract (en)

[origin: EP1517083A1] Device for thermally treating process waste gases containing pollutants comprises a combustion chamber (1) containing a burner with a process waste gas feed, a feed (2) for scrubbing liquid which forms a film for the removing of particles on the inner wall of the combustion chamber and a removal line for waste gas and scrubbing liquid. The feed for the scrubbing liquid is arranged directly below the lid (3) and structured so that a closed film (11) forms on the whole inner casing surface of the combustion chamber according to the gravitational force. The part of the lid facing the inside of the combustion chamber is not wetted by the scrubbing liquid.

IPC 8 full level

F23G 7/06 (2006.01); **F23C 5/32** (2006.01); **F23D 1/00** (2006.01); **F23Q 9/00** (2006.01)

CPC (source: EP US)

F23G 7/065 (2013.01 - EP US); **F23D 2900/00016** (2013.01 - EP US); **F23G 2208/00** (2013.01 - EP US)

Cited by

CN109642725A; EP1933088A3; US8591819B2; US10920981B2

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